

IFW



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Pas

Docket No.: TI-22398.1

Serial No.: 10/656,312

Art Unit: 1765

Filed: 09/05/2003

Examiner: Ahmed, Shamim

Title: System and Method for Integrating Oxide Removal and Processing Of a Semiconductor Wafer

AMENDMENT UNDER 37 C.F.R. §1.111

August 13, 2004

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Commissioner:

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(A)	
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service on <u>8-13-04</u>	
as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450	
<u>Karen Vertz</u> Karen Vertz	<u>8-13-04</u> Date

In response to the Notice of Non-Compliant Amendment, dated 08/03/2004, in the above-identified patent application, please accept the following corrected amendments. They are respectfully submitted as a full and complete response to that Action. Charge any required fees to the deposit account of Texas Instruments Incorporated, Account No. 20-0668.